



**Field-Emission Scanning Electron Microscope (FE-SEM):** FESEM Supra55 Zeiss, provides excellent imaging properties combined with analytical capabilities makes this high end FE-SEM suitable for a wide range of applications in materials science, life science and semiconductor technology. The large specimen chamber for the integration of optional detectors and accessories enables the user to configure the SUPRA for specific applications without sacrificing productivity or efficiency.

- GEMINI Technology with high efficiency in-lens detector and no magnetic field at specimen level
- Superb resolution and image quality at high and low operating voltages
- Extremely wide operating voltage range from 0.02-30kV
- Designed-in ease of use with minimal adjustments required when changing operating conditions
- Short analytical working distance of 8.5 mm for simultaneous high resolution imaging and X-ray analysis
- High probe current (up to 100 nA) with high stability (better than 0.2%/h) for precise analytical results
- Variable Pressure (VP) mode up to 133Pa for superb imaging of non conductive samples
- Multi-User friendly with Windows® based SmartSEM control software